



### LABORATORY OF SPECTROSCOPY



LATVIJAS UNIVERSITĀTES CIETVIELU FIZIKAS INSTITŪTS

INSTITUTE OF SOLID STATE PHYSICS University of Latvia Dr. phys. Anatolijs Šarakovskis

#### **KEY NUMBERS OF LABORATORY**

- Staff 38 people
  - 19 Dr., including 2 postdocs
  - 17 students, including 7 PhD students
- Ongoing projects 19
  - 4 national research grants,
  - 1 ERA-NET,
  - 4 European Research & Development Fund,
  - EUROfusion,
  - National Research Programme "Collaboration with CERN"





To become an internationally significant partner for collaboration with scientists and industry

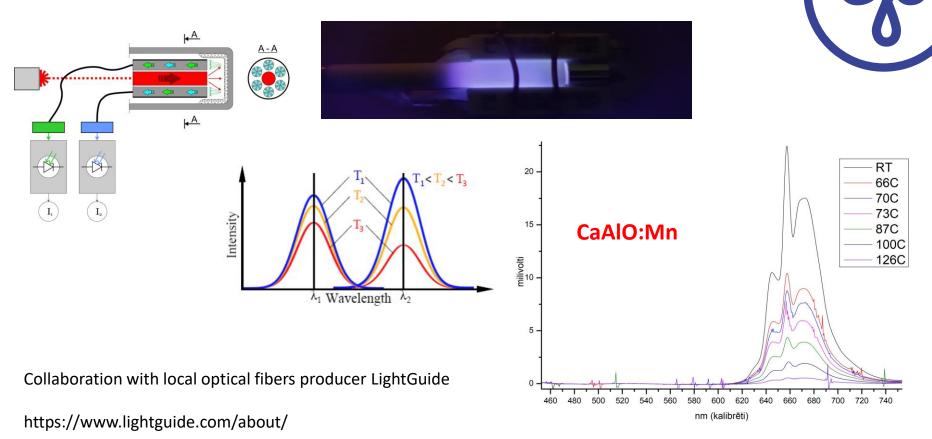
The laboratory is involved in research projects and provides service in spectroscopy research for other laboratories, academic institutions and industry

Few examples of the research projects:

- All-optical temperature sensors
- Scintillators
- Persistent luminophors
- Upconversion luminescence



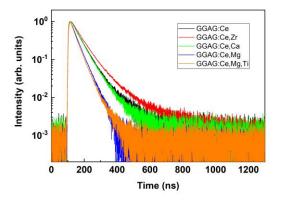
#### ALL OPTICAL TEMPERATURE SENSOR





# CERIUM DOPED GGAG UNDER SYNCHROTRON RADIATION

AVGa



A – dodecahedron; B– octahedron; C– tetrahedron.

> The role of intrinsic defects on the luminescence and scintillation performance of codoped GGAG:Ce<sup>3+</sup> single crystals has been elucidated.

550

600

Wavelength (nm)

650

700

750

• The fundamental mechanisms of energy transfer processes in codoped GGAG:Ce<sup>3+</sup> single crystals have been elucidated.

V. Pankratova, et. al., Scientific Reports 10 (2020) 20388 A.P. Kozlova, ..., V. Pankratov, Results in Physics 16 (2020) 103002

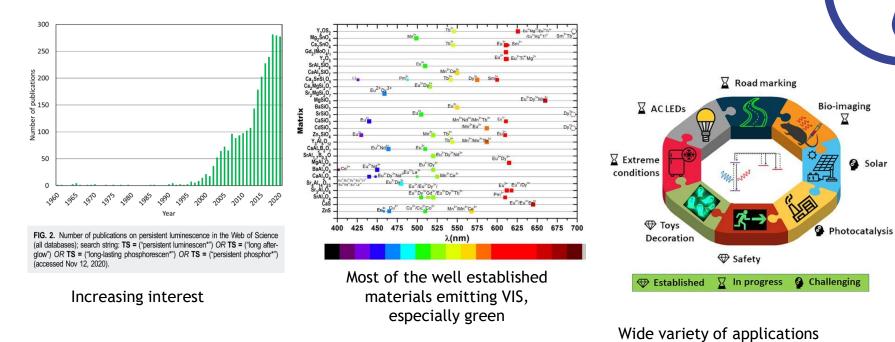
450

500



# Ni, **CERIUM DOPED GGAG UNDER SYNCHROTRON RADIATION** DESY Monochromator with plane mirror (M2) and two plane gratings orroidal Mirro Andor Shamrock spect

#### PERSISTENT LUMINESCENCE



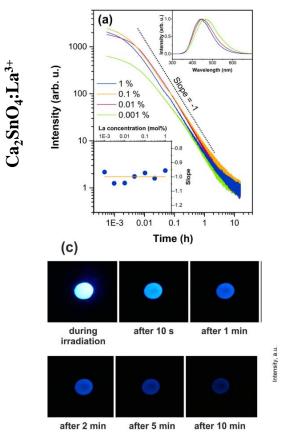
T. Lécuyer et al., "Chemically engineered persistent luminescence nanoprobes for bioimaging," Theranostics, vol. 6, no. 13, pp. 2488–2523, 2016.

R. E. Rojas-Hernandez, et al. Renew. Sustain. Energy Rev., vol. 81, no. June 2017, pp. 2759–2770, 2018.

D. Poelman, et al. Persistent phosphors for the future: Fit for the right application. J. Appl. Phys. 128, 240903 (2020).

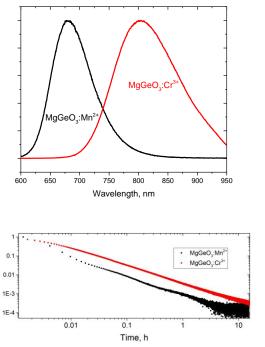


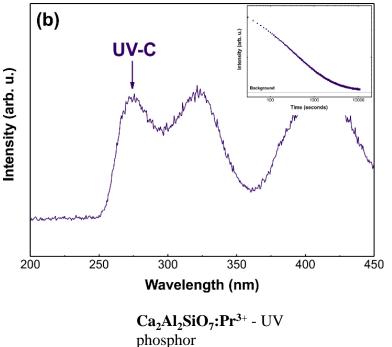
#### PERSISTENT LUMINESCENCE



Latvian Council of Science grants:

- Novel persistent luminescent material red light emitter
- Defect engineering of novel UV-C persistent phosphor materials

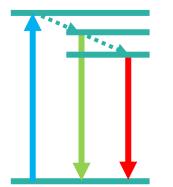


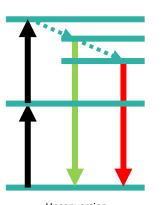








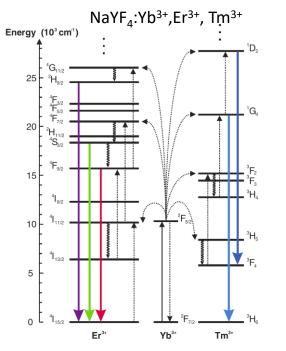




Traditional photoluminescence

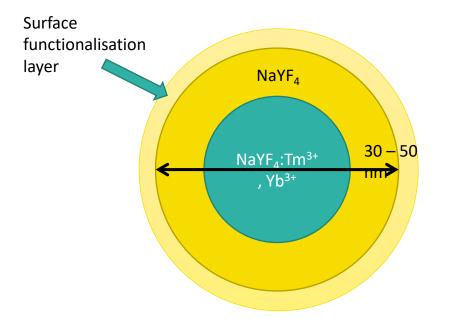
Visible luminescence excited by blue or ultraviolet radiation Upconversion luminescence

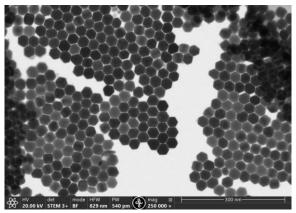
Visible luminescence excited by red or infrared radiation



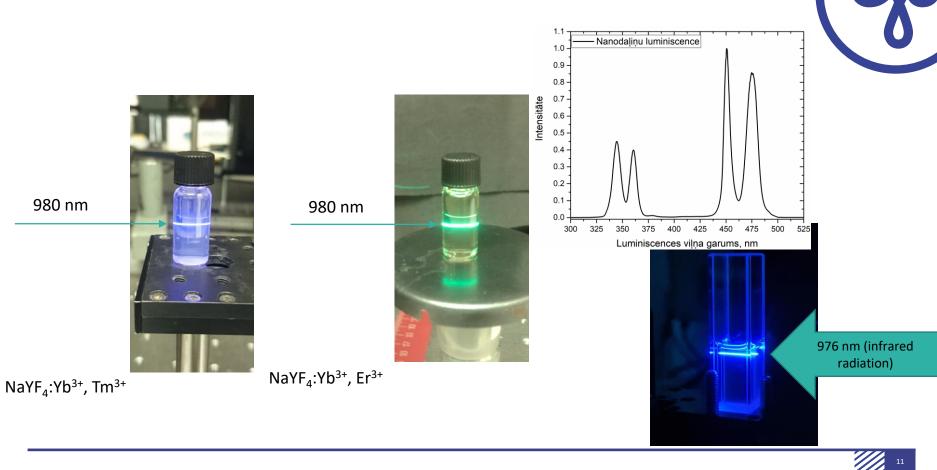




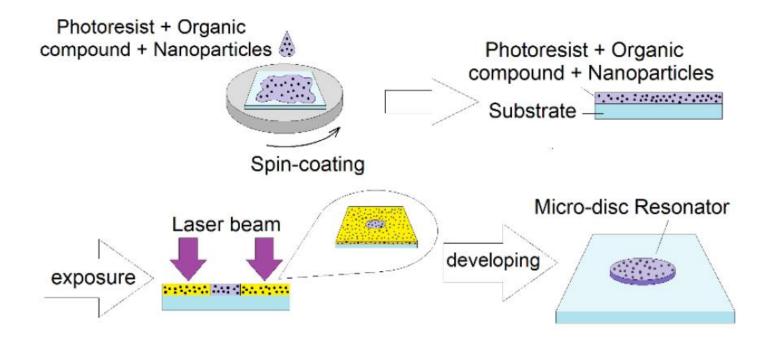










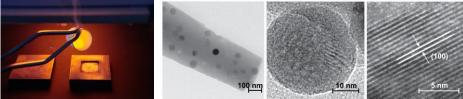


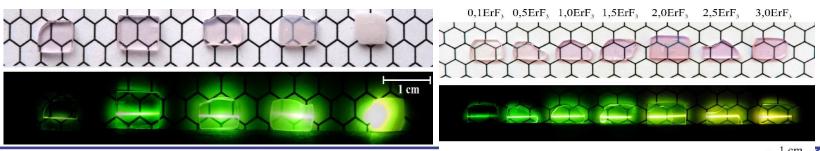


Synthesis and optical properties of oxyfluoride glass ceramics



- Broad range of fluoride microcrystals and nanocrystals doped with transition and rare-earth ions: CaF<sub>2</sub> - BaF<sub>2</sub>, LaF<sub>3</sub>, YF<sub>3</sub>, NaREF<sub>4</sub> and others.
- Oxyfluoride glass ceramics: SiO<sub>2</sub> matrix with nanocrystallites (fluorides) for lighting applications







#### **KEYFACTS ABOUT THE LABORATORY - COMPETENCES**

 Generation and transformation of defects including radiation defects in solids



- Complex oxides for scintillator applications
- Upconversion luminescence in different materials
- Materials for all-optical temperature sensors
- Broad variety of different experimental tools for spectroscopic characterization of materials



#### **KEYFACTS ABOUT THE LABORATORY - SERVICE**







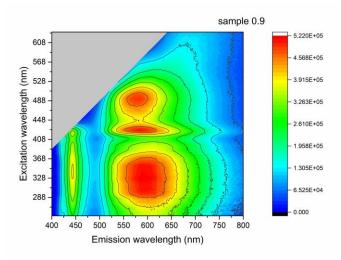
#### **KEYFACTS ABOUT THE LABORATORY - SERVICE**

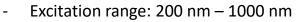




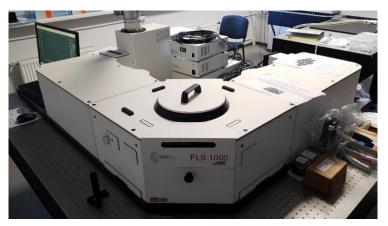


• UV-VIS-IR optical spectroscopy Edinburgh Instruments spectrometer

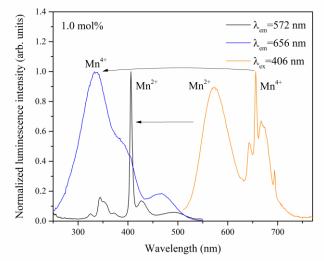




- Detection range: 200 nm 870 nm
- Quantum yield measurements









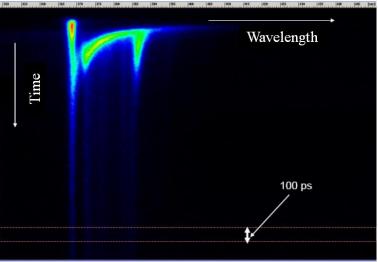
• UV-VIS-IR optical spectroscopy

Tunable nanosecond, picosecond and femtosecond laser systems



- Excitation range: 210 nm 2600 nm
- Detection range: 200 nm 850 nm
- Pulse duration/frequency: 5ns/10Hz, 27 ps/1kHz, 190 fs/1MHz
- Temporal resolution: up to 20 ps. Streak-camera, TCSPCs
- Temperature range: 5 K 330 K

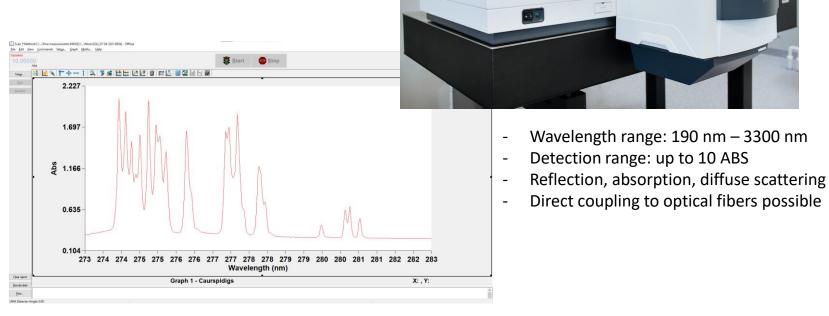






• UV-VIS-IR optical spectroscopy Cary 7000 spectrophotometer







• UV-VIS-IR optical spectroscopy





- Wavelength range: 190 nm 3300 nm
- Detection range: up to 10 ABS
- Reflection, absorption, diffuse scattering
- Direct coupling to optical fibers possible



• Vibrational spectroscopy

FTIR Vertex 80v



0,04 T=6,8K Absorbance 20'0 ž WWWWWW 0,01 260 280 300 320 340 360 380 400 420 440 240 Wavenumbers (cm<sup>-1</sup>)

320

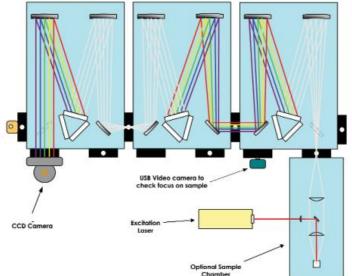
Sample 52TOP2

- Spectral range: 10 000 cm<sup>-1</sup> 5 cm<sup>-1</sup>
- Spectral resolution: < 0.1 cm<sup>-1</sup>
- Microscope spatial resolution: 20  $\mu m$

Ultrasmall concentrations of contaminants (in the range of ppt (10<sup>-12</sup>) in silicon can be measured



- Vibrational spectroscopy
- Raman spectrometer TriVista CRS





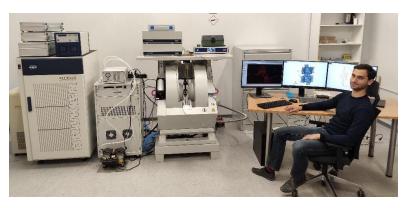
- Lasers: 1064 nm, 785 nm, 632.8 nm, 532 nm
- Detection: triple monochromator with CCD camera
- Spectral resolution: < 0.15 cm<sup>-1</sup>
- Microscope: confocal microscope with submicron resolution

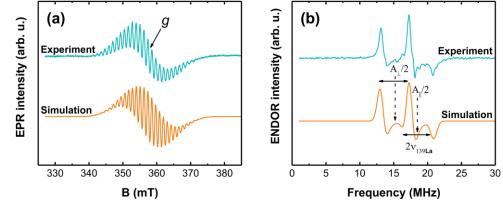




• Magnetic spectroscopy

#### EPR spectrometer Elexsys-II E500 CW





- Magnetic field range: 0 1.7 T
- Temperature: 4 K 300 K
- X-band: 9.2 GHz 9.9 GHz; 200 mW
- Q-band: 33.85 GHz 34.15 GHz, 80 mW
- ENDOR option

(a) EPR and (b) ENDOR spectra confirming hyperfine interaction between Cr<sup>5+</sup> and La nuclei in LaOCI: Cr

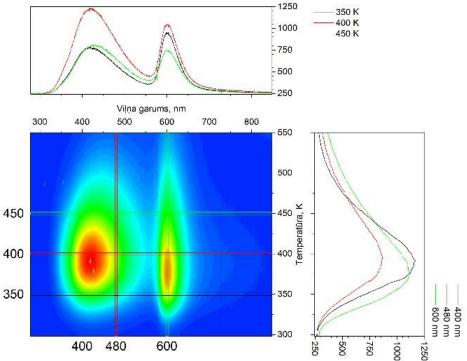


• Dosimetric properties

#### **TL-OSL reader Lexsyg research**



- Irradiation source: x-ray or beta
- Heating range: RT 700 °C
- Heating rate: 0.1-20 °C/s
- Maximum number of samples: 80







- Ellipsometry
- Spectroscopic ellipsometer RC2-XI (Woollam)

- Wavelength range: 210 nm-1690 nm
- Angles of incidence: 45°-90°
- Beam size: 120 μm
- Temperature range: -50°C-150°C

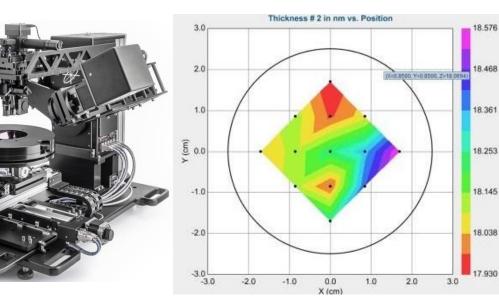


A light beam with known polarisation is reflected from the sample, and the output polarisation is measured. Ellipsometry measures the change in amplitude and phase of a reflected polarised light.

One of the features of our spectroscopic ellipsometer is a possibility to perform a sample mapping: a specific measurement will be repeated at several points of the sample. This is a fast and efficient way to control, e.g., the uniformity of the film thickness.

This figure describes the variations of thickness of  $HfO_2$  thin film obtained by 13-point mapping of optical constants of the sample.









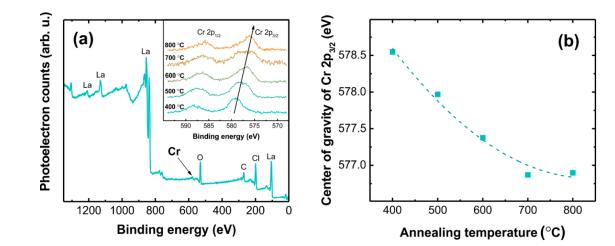
- Identification and quantification of \_ individual chemical states
- Depth profiling by Ar ion etching -
- Spatial resolution: <1 µm
- UPS
- REELS
- ISS



Electron spectroscopy

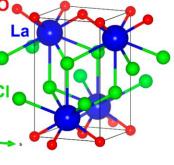
**XPS/UPS** system





**Figure 6.** (a) XPS spectrum of the 5% Cr LaOCl sample prior annealing in a reducing atmosphere; inset: background corrected XPS spectra in Cr 2p peak range of 5% Cr LaOCl samples annealed at different temperatures in  $H_2$ /Ar atmosphere and (b) binding energy of Cr  $2p_{3/2}$  to the annealing temperature of the samples.

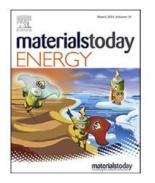




Citation: Antuzevics, A.; Krieke, G.; Ozols, H.; Fedotovs, A.; Sarakovskis, A.; Kuzmin, A. Oxidation State and Local Structure of Chromium Ions in LaOCl. *Materials* 2021, *14*, 3539. https:// doi.org/10.3390/ma14133539

Electron spectroscopy

**XPS/UPS** system



Thickness-dependent properties of ultrathin bismuth and antimony chalcogenide films formed by physical vapor deposition and their application in thermoelectric generators

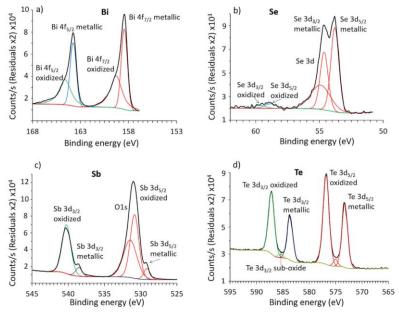




Fig. 2. Representative deconvoluted XPS spectra of a-b) 6 nm thin Bi<sub>2</sub>Se<sub>3</sub> film and c-d) 5 nm thin Sb<sub>2</sub>Te<sub>3</sub> film deposited on mica substrates. XPS, X-ray photoelectron spectroscopy.

#### Table 1

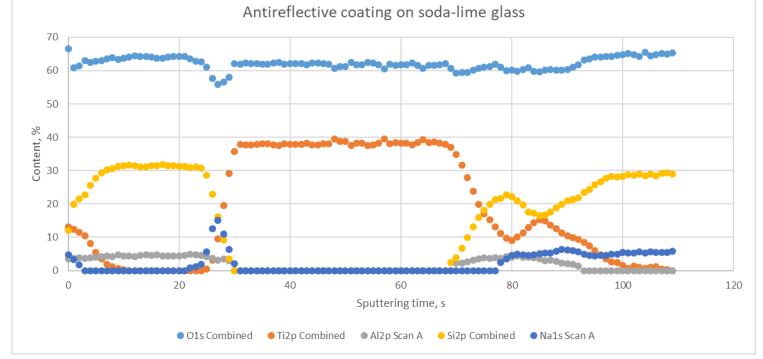
Comparison of the chemical compositions of the Bi<sub>2</sub>Se<sub>3</sub> and Sb<sub>2</sub>Te<sub>3</sub> source materials and ultrathin films deposited on mica substrates revealed by the XPS measurements.

Chemical element	Bi <sub>2</sub> Se <sub>3</sub> source material	Bi <sub>2</sub> Se <sub>3</sub> 6 nm thin film on mica	Chemical element	Sb <sub>2</sub> Te <sub>3</sub> source material	$Sb_2Te_3$ 5 nm thin film
	at %	at %		at %	at %
Bi	37.1	36.7	Sb	41.6	44.9
Se	62.9	63.3	Te	58.4	55.1



• Electron spectroscopy

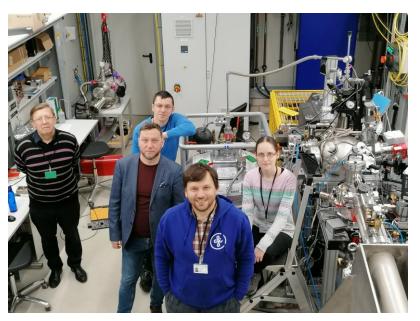
#### XPS/UPS system







• Large Scale Facilities - synchrotrons [DESY (Hamburg), MAX IV (Lund)] - excitation in vacuum ultraviolet region















## LOOKING FORWARD TO POSSIBLE COLLABORATION







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